

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Gaillard, et al.

Serial No.: 10/789,209

Filed:

February 27, 2004

Confirmation No.: Unknown

For:

Method of Decreasing the

K Value in SIOC Layer Deposited by Chemical

Vapor Deposition

Group Art Unit: Unknown

Examiner:

Unknown

MAIL STOP AMENDMENT Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

CERTIFICATE OF MAILING 37 CFR 1.8

I hereby certify that this correspondence is being deposited on //9, 2004 with the United States Postal Service as First Class Mail in an envelope addressed to: Mail Stop Amendment, Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450.

PRELIMINARY AMENDMENT

Prior to examination, please amend the above-identified application as shown below. Amendments to the Specification begin on page 2. The Pending Claims begin on page 3. Remarks begin on page 7.